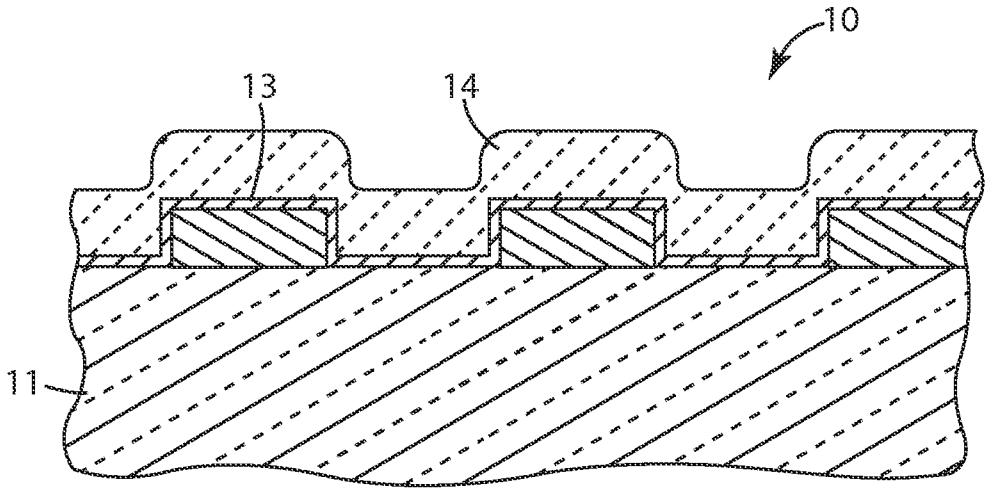



FIG. 1

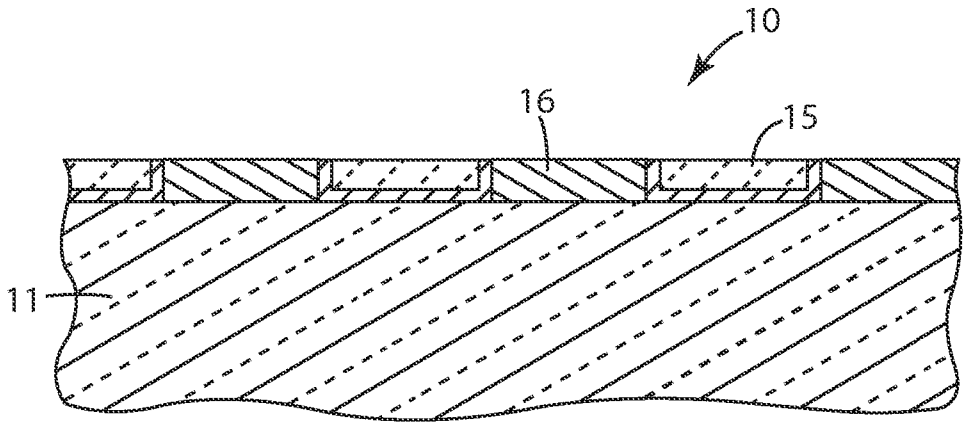



FIG. 2

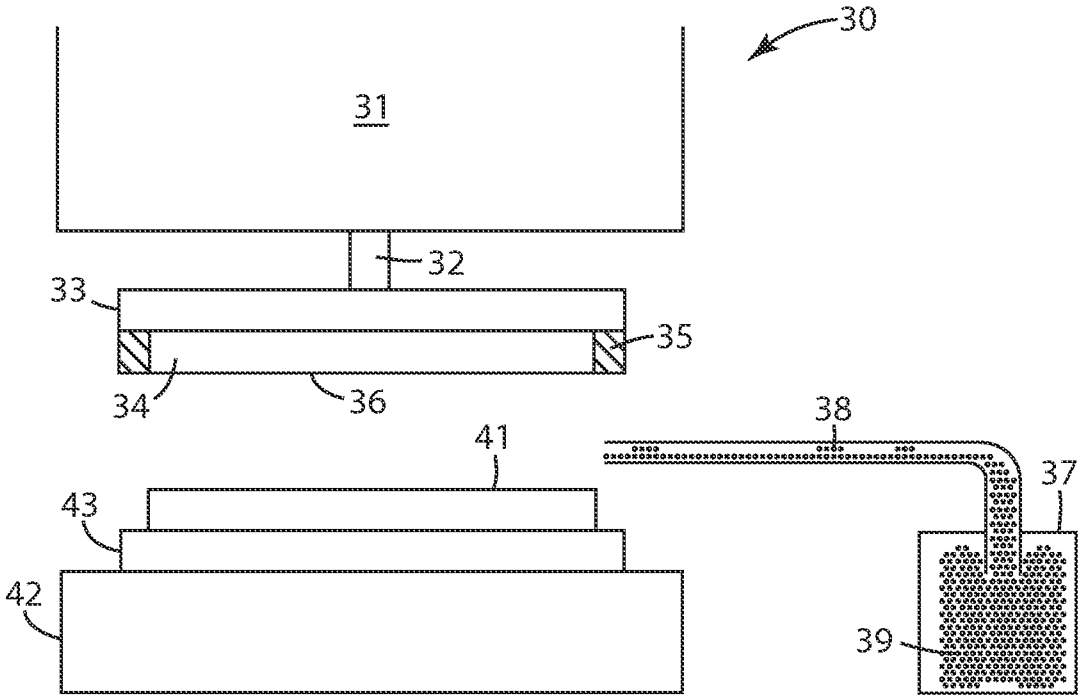



FIG. 3

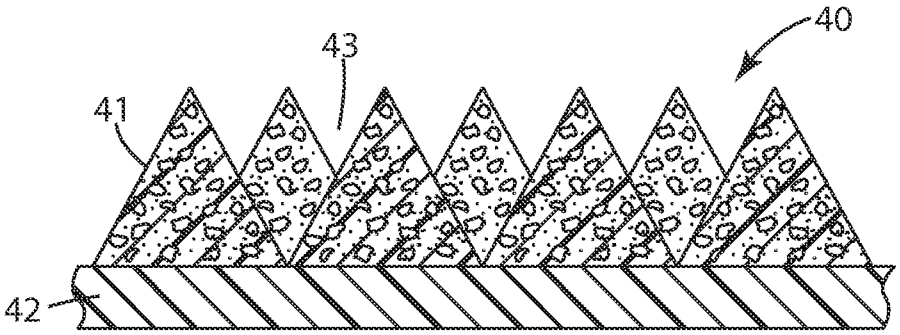



FIG. 4

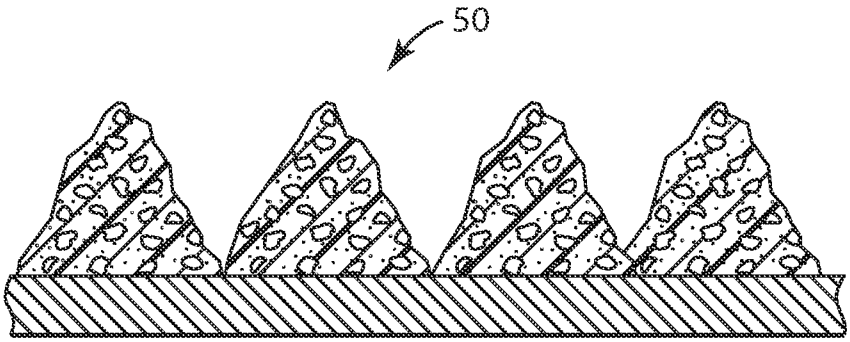



FIG. 5

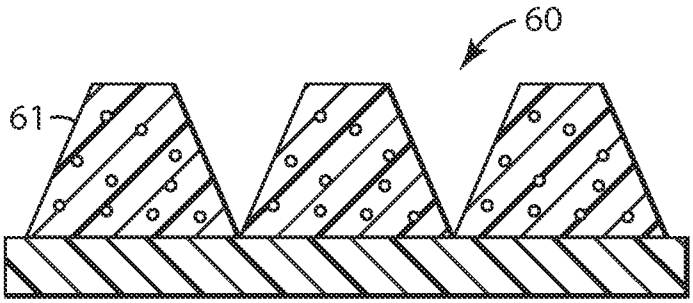



FIG. 6

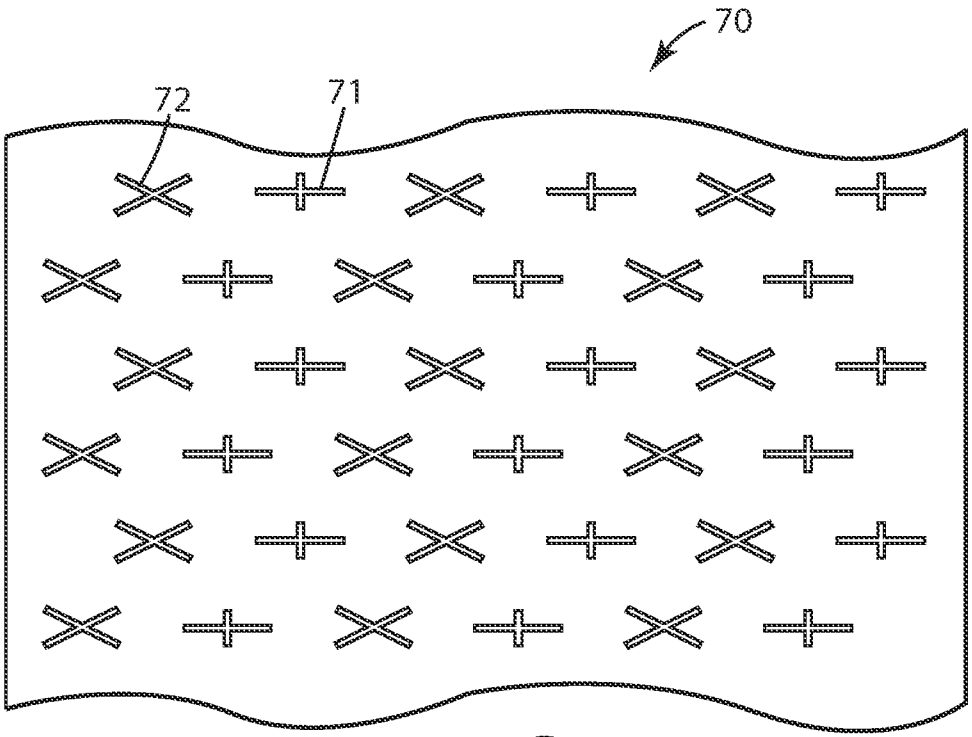



FIG. 7

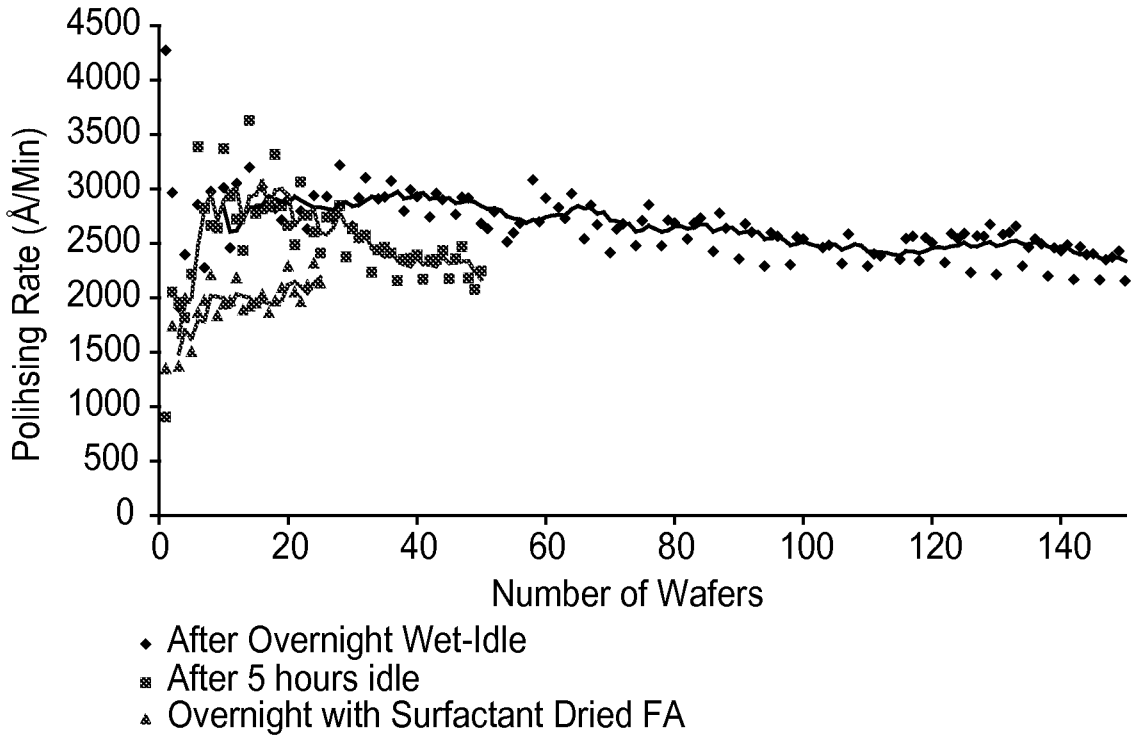

Polihsing Rate (Å/Min)
4500
4000
3500
3000
2500
2000
1500
1000
500
0
0
20
40
60
80
100
120
140
Number of Wafers
After Overnight Wet-Idle
After 5 hours idle
Overnight with Surfactant Dried FA

*FIG. 8*